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Supporting information for article:

**Study on the vertical Bridgman method of melt-grown CsPbBr₃
single crystals for nuclear radiation detection**

**Mingzhi Zhang, Chentao Huang, Guotu Xia, Juan Liu, Fang Tian, Jijun Zou and
Bin Tang**

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Section S1. The experimental details for wafer treatment and detector fabrication

1.1 Wafer surface treatment

The diamond wire cutting machine STX-202A (*Shenyang Kejing Automation Equipment Co., LTD*) was used to cut the CsPbBr₃ single crystal. To remove the damage layer, a series of careful treatments were performed on the wafer surface. Al₂O₃ abrasives with 14 μm in diameter and then 7 μm, 1.5 μm and 0.5 μm were used to polish the surfaces of the wafer in turns. Then the polished wafers were immersed in a concentration of 5% bromine methanol solution for 30 s to remove the physical damage of the surface caused by the cutting and mechanical polishing processes. At last, a thin surface passivation layer about several nanometer was made using dilute hydrobromic acid, and covered uniformly on the wafer surface.

1.2 Detector fabrication

Planar circular symmetric composite Ni/Ti metal electrodes with 6mm in diameter and totally 100 nm thick were made by deposition on both side of the well-treated wafer surfaces. After electrode fabrication, the detector was annealed in vacuum drying box under 80 °C for 24h to strengthen the metal-semiconductor contact. Then the detectors were bonded by Au wire to connect with the charge collection circuit which was self-designed on a printed circuit board (PCB).

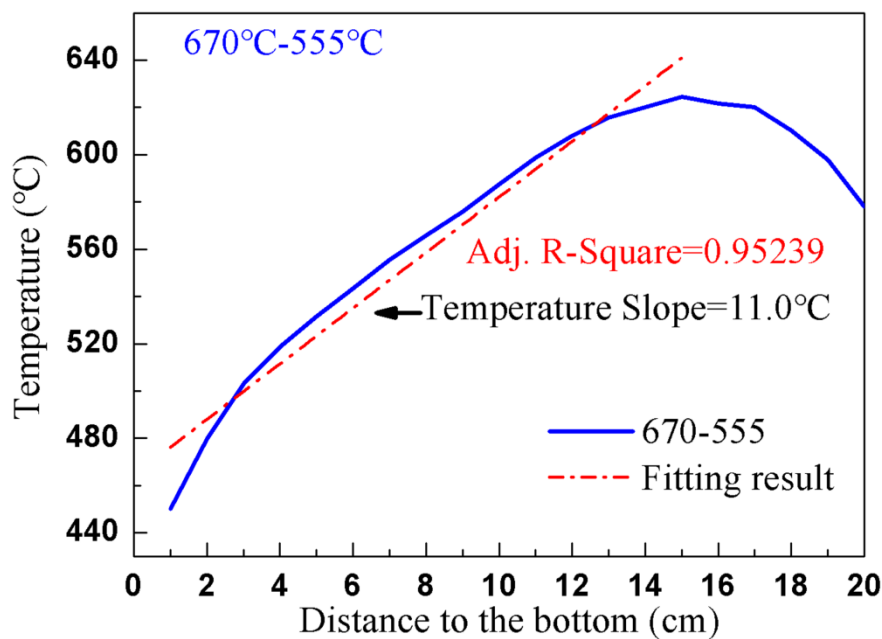
Section S2. The temperature curve with various temperature settings of the furnace

Figure S1. Temperature profile with 11.0°C/cm gradient of the Bridgman tube furnace

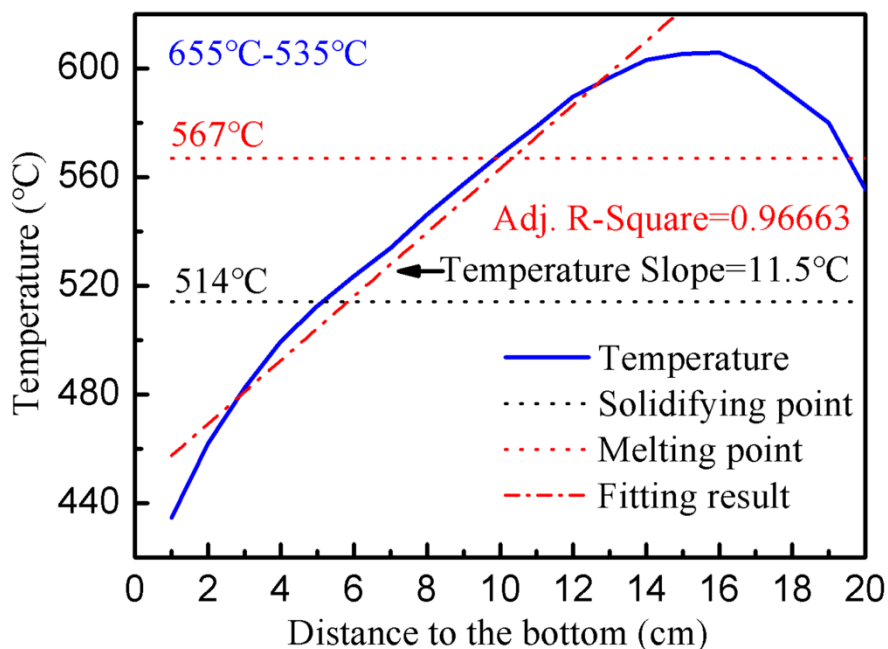


Figure S2. Temperature profile with 11.5°C/cm gradient of the Bridgman tube furnace

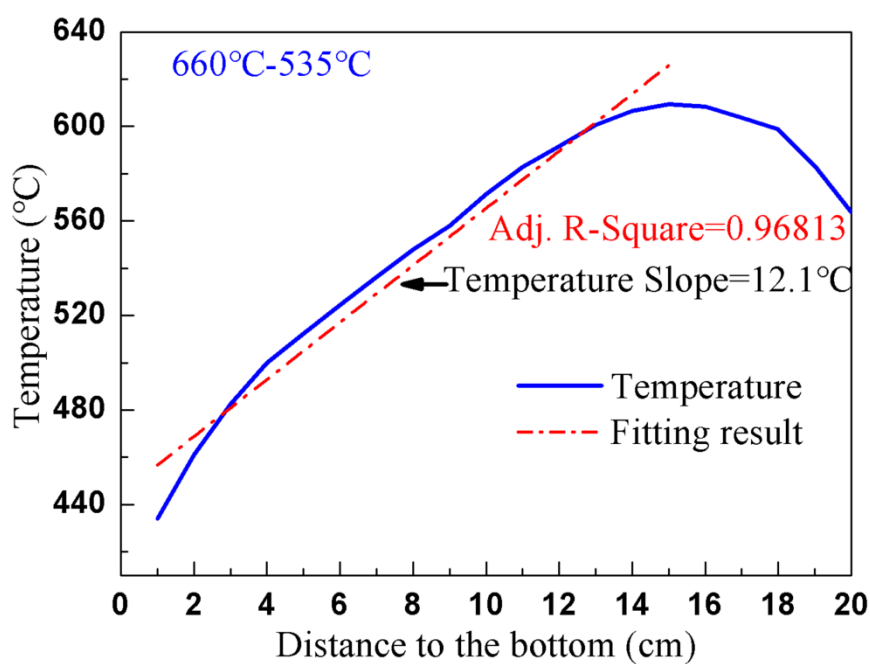


Figure S3. Temperature profile with 12.1°C/cm gradient of the Bridgman tube furnace

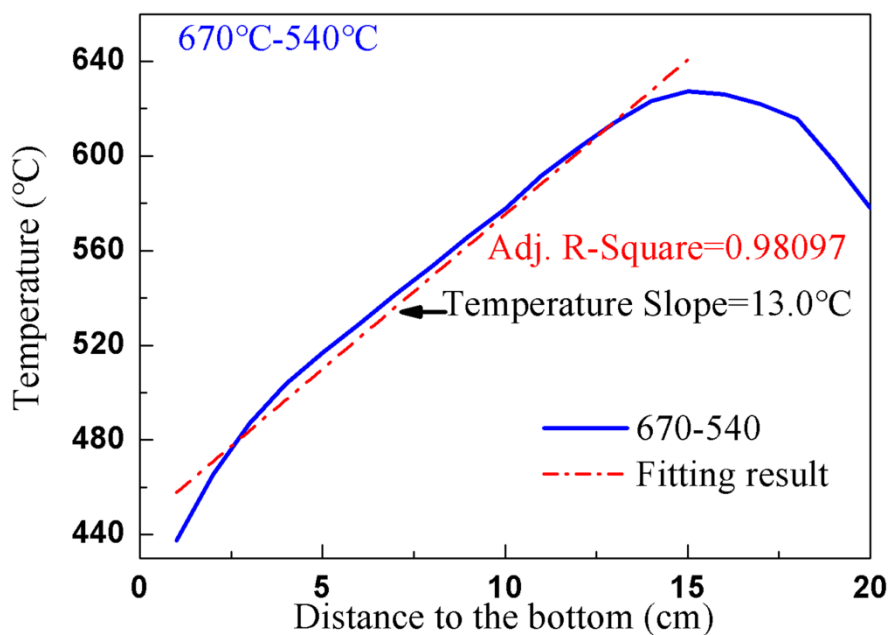


Figure S4. Temperature profile with 13.0°C/cm gradient of the Bridgman tube furnace

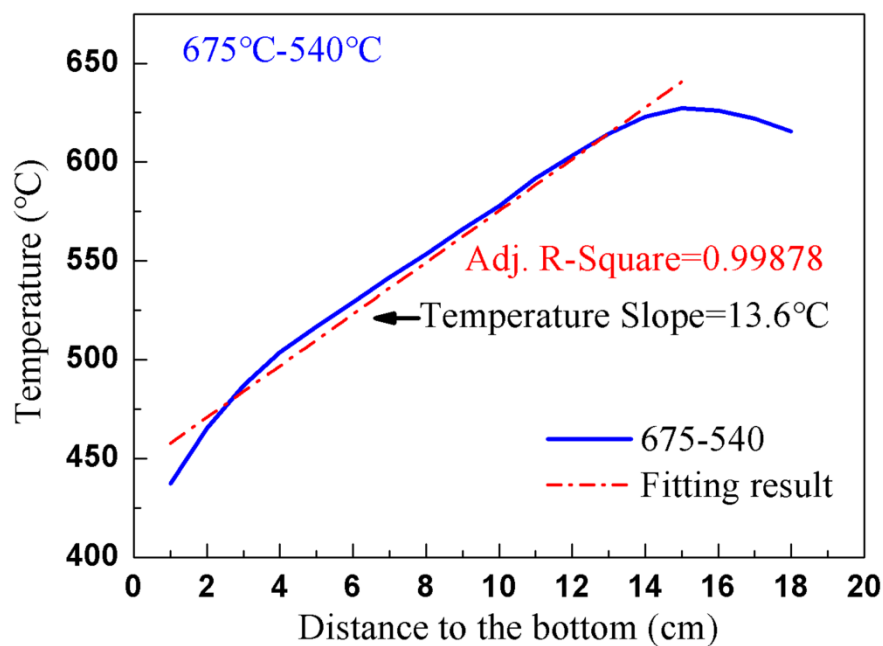


Figure S5. Temperature profile with 13.6°C/cm gradient of the Bridgman tube furnace

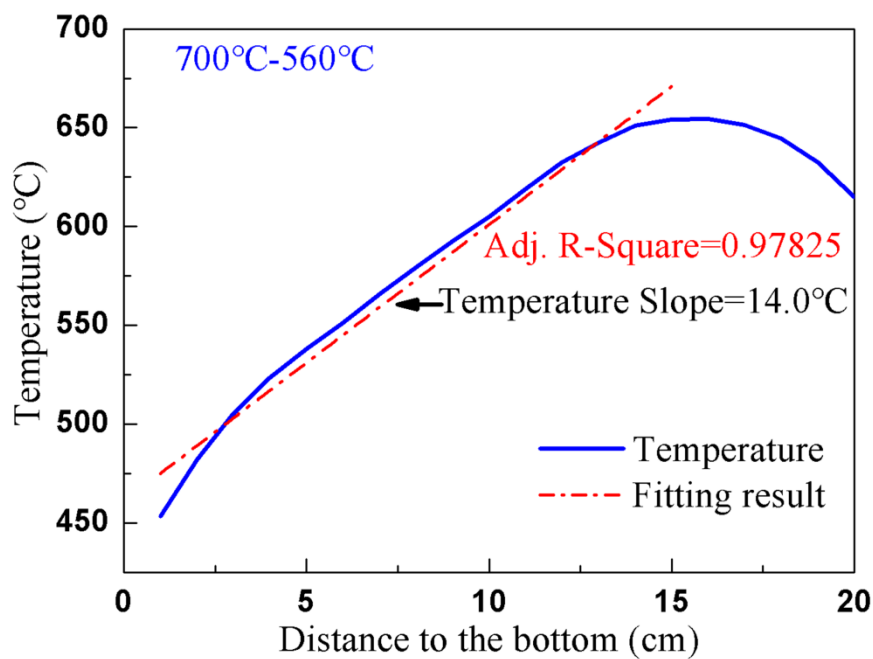


Figure S6. Temperature profile with 14.0°C/cm gradient of the Bridgman tube furnace

Section S3. The influence of crystal parameters for crystal growth

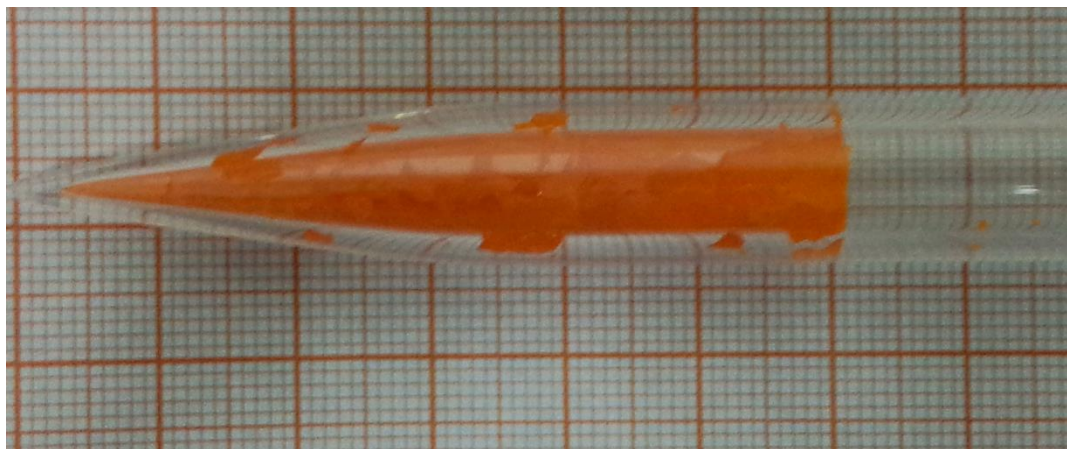


Figure S7. Crystal growth with temperature gradient 3.5°C/cm

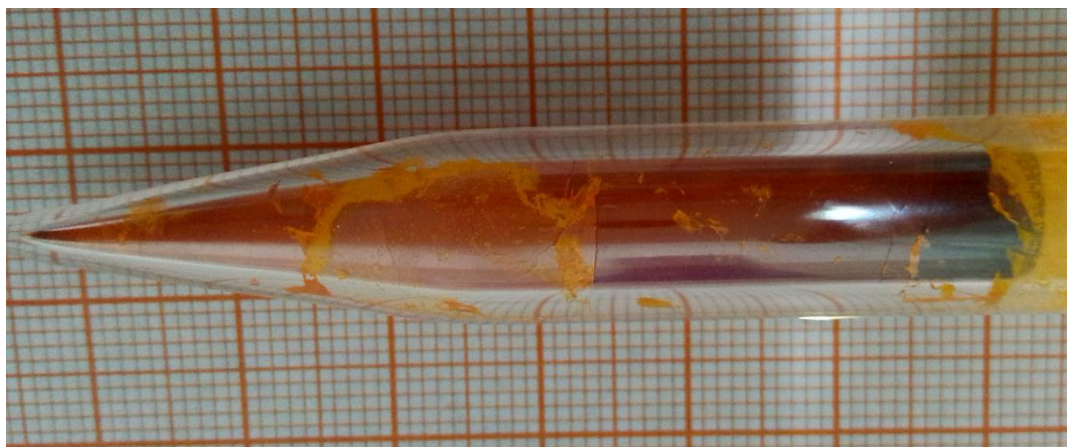


Figure S8. Crystal growth with temperature gradient 5.0°C/cm



Figure S9. Crystal growth with temperature gradient 8.0°C/cm



Figure S10. Crystal growth with a growth rate of 1.0 mm/hr.



Figure S11. Crystal growth with a growth rate of 0.2 mm/hr.

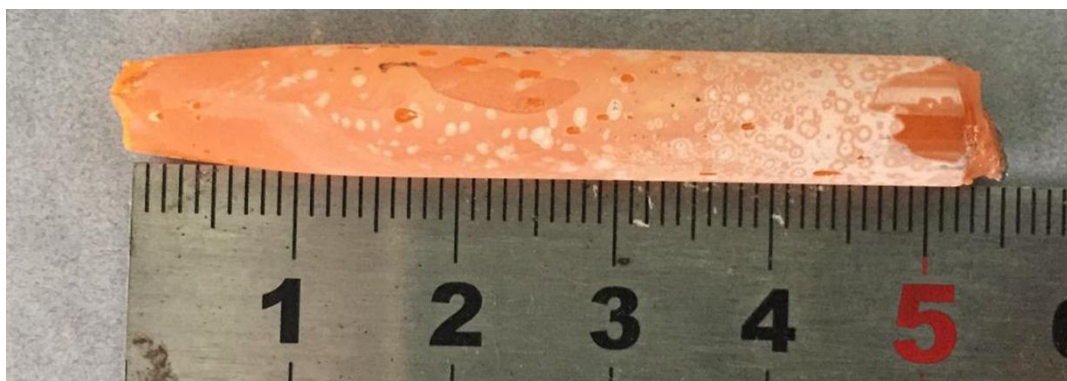


Figure S12. Crystal growth with a growth rate of 0.18 mm/hr.

Reference

- Zhang, M., Yang, Y., Xia, G., Zou, J., Deng, W., Tian, F. & Deng, J. (2022). *ACS Appl. Nano Mater.* **5**, 16039-16044.
- Dhanaraj, G., Byrappa, K., Prasad, V. & Dudley, M. (2010). *Springer Handbook of Crystal Growth*, pp. 159-195, 1st ed. Springer Science & Business Media, USA.
- Pan L., Kandlakunta P., Cao L.R. Inorganic Perovskite CsPbBr₃ Gamma-Ray Detector. *Advanced Materials for Radiation Detection*. Springer, Cham., **2022**, 33~54. Pan, L., Kandlakunta, P. & Cao, L. R. (2021). In *Advanced Materials for Radiation Detection*, edited by K. Iniewski, pp. 33-54. Cham: Springer.
- Zhang, M., Zheng, Z., Fu, Q., Guo, P., Zhang, S., Chen, C., Chen, H., Wang, M., Luo, W. & Tian, Y. (2018). *J. Phys. Chem. C*, **122**, 10309-10315.